Please	type a	plus	sign	(+)	inside	this box	
--------	--------	------	------	-----	--------	----------	--

PTO/SB/08A (08-00)
Approved for use through 10/31/2002. OMB 0651-0031
U.S. Patent and Trademark Office: U.S. DEPARTMENT OF COMMERCE

Under the Paperwork Reduction Act of 1995, no persons are required to respond to a collection of information unless it contains a valid OMB control number.

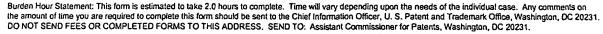
Substitu	Substitute for form 1449A/PTO		Complete if Known			
15.E	20114710110	1001 001105	Application Number	Not yet assigned		
	DRMATION D		Filing Date	August 20, 2003		
STATEMENT BY APPLICANT		First Named Inventor	Walton			
			Group Art Unit	Not yet assigned		
(use as many sheets as necessary)		Examiner Name	Not yet assigned			
Sheet	1	of o	Attorney Docket Number	NC 84 613		

				U.S. PATENT DOCU	MENTS	
Examiner	Cite	U.S. Patent		Name of Patentee or Applicant	Date of Publication of	Pages, Columns, Lines, Where Relevant
Initials"	No.1	Number	Kind Code ² (<i>if known</i>)	of Cited Document	Cited Document MM-DD-YYYY	Passages or Relevant Figures Appear
		5,182,496		Manheimer et al	01/26/1993	
		5,874,807		Neger et al	02/23/1999	
						
		 				
					 	· /
		 			 	
		ļ				
						
		ļ				
		ļ	_			
		}				

				FOR	EIGN PATENT DOCUMENT	S		
Examiner Initials*	Cite No.1	Office ³	Foreign Patent Doo Number ⁴	cument Kind Code ⁵ (if known)	Name of Patentee or Applicant of Cited Document	Date of Publication of Cited Document MM-DD-YYYY	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear	1e
						 		
						 		
		 -			 	 		╂╾┥
		 			 	+		+-
			 			 		$\dagger \exists$

Examiner	Date	
Signature	Considered	

¹ Unique citation designation number. ² See attached Kinds of U.S. Patent Documents. ³ Enter Office that issued the document, by the two-letter code (WIPO Standard ST.3). ⁴ For Japanese patent documents, the indication of the year of the reign of the Emperor must precede the serial number of the patent document. ⁵ Kind of document by the appropriate symbols as indicated on the document under WIPO Standard ST. 16 if possible. ⁶ Applicant is to place a check mark here if English language Translation is attached.



^{*}EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

Please type a plus sign (+) inside this box	→	
---	---	--

PTO/SB/08B (08-00)

Approved for use through 10/31/2002. OMB 0651-0031

U. S. Patent and Trademark Office: U.S. DEPARTMENT OF COMMERCE

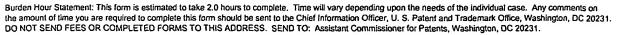
Under the Paperwork Reduction Act of 1995, no persons are required to respond to a collection of information unless it contains a valid OMB control number.

Substitu	ute for form 1449B/PTO	RMATION DISCLOSURE EMENT BY APPLICANT (use as many sheets as necessary) Application Number Not yet assigned August 20, 2003 Filting Date August 20, 2003 First Named Inventor Walton Group Art Unit Not yet assigned Examiner Name Not yet assigned			
				Application Number	Not yet assigned
	SCLOSURE	Filing Date	August 20, 2003		
	APPLICANT	First Named Inventor Walton			
STATEMENT BY APPLICANT				Group Art Unit	Not yet assigned
	(use as many st	heets	as necessary)	Examiner Name	Not yet assigned
Sheet	2	of	2	Attorney Docket Number	NC 84,613

	_	OTHER PRIOR ART - NON PATENT LITERATURE DOCUMENTS	7
Examiner nitials	Cite No. ¹	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.	T²
		MEGER et al, "Bemed-Generated Plasmas for Processing Applications", Amer. Inst. of Physics, May 2001, Vol. 8 No. 5, pp. 2558-2564	
		LEONHARDT et al, "Plasma Diagnostic in Large area Plasma Processing System", Journal of Vacuum Science & Tech., July 2001, Vol. 19 No. 4, pp. 1367-1373	
		WALTON et al, "Ion Energy Distribution in a Pulsed, Electron Beam-Generated Plasma", Journal of Vacuum Science & Tech., July 2001, Vol 19 No. 4, pp. 1325-1329	
		MANHEIMER et al, "Theoretical Overview of the Large-Area Plasma Processing System (LAPPS)", Plasma Sources Science Technology, 2000, Vol 9, pp. 370-386	
		FERNSLER et al, "Production of Large-Area Plasmas by Electron Beams", Amer. Inst. of Physics, May 1998, Vol5 No. 5, pp. 2137-2143	
		·	
			<u> </u>
			-
Examine		Date	_

^{*}EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

Signature



Considered

¹ Unique citation designation number. ² Applicant is to place a check mark here if English language Translation is attached.